


### Introduction to Atomic Force Microscope

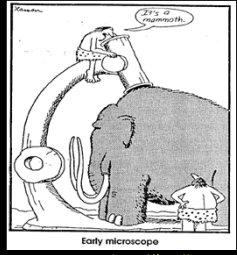


Not that kind of "atomic"

Tien-Ming Chuang (莊天明)  
Institute of Physics, Academia Sinica

1

### Introduction to Scanning Force Microscope



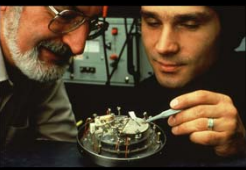
Early microscope

Tien-Ming Chuang (莊天明)  
Institute of Physics, Academia Sinica

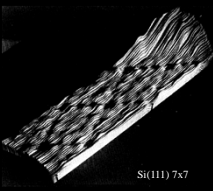
2

### Scanning Tunneling Microscope (STM)

Applicable only to conducting samples.



Heinrich Rohrer & Gerd Binnig  
Nobel Prize in 1986  
©IBM



Si(111) 7x7


G. Binnig et al., Phys. Rev. Lett. 49, 57 (1982)

G. Binnig et al., Phys. Rev. Lett. 50, 120 (1983)


3

### Invention of Atomic Force Microscope (AFM)

- One of the most versatile analytical tools to appear on the research scene in a century.
- No. 4 of Most Cited PRL papers as in November, 2002.



First AFM in Science Museum, London



Gerd Binnig  
© Nobel Foundation

Calvin Quate  
© Stanford

Christoph Gerber  
© University of Basel

But no atomic resolution then!

G. Binnig et al., Phys. Rev. Lett. 56, 930-933 (1986)

4

### Invention of Atomic Force Microscope (AFM)

Seeing by feeling the force!  
Hooke's Law at atomic scale!

The Concept



5



What force?

6

### Tip-Sample Forces : Microscopic Description

- The Lennard-Jones potential:
 
$$V_{Lennard-Jones} = 4\epsilon \left( \left( \frac{\sigma}{r} \right)^{12} - \left( \frac{\sigma}{r} \right)^6 \right)$$
 van der Waals, attractive  
 Short range, Pauli + chemical, repulsive

7

### Long Range Tip-Sample Forces : Magnetic Force

- If the tip were coated with magnetic material, it would be sensitive to the stray field from the surface.
- Due to the extent of the tip geometry, the force acting on the tip is the integral over all the dipole moments on the tip:
 
$$F_{mag} = \int_{tip} \vec{m}_{tip}(\vec{r}) \cdot \nabla \vec{B}_{sample}(\vec{r}) d\vec{r}$$

8

### Long Range Tip-Sample Forces : Electrostatic Force

- The strength and distance dependence of electrostatic forces obey Coulombs law.
- Electrostatic forces :
 
$$F_{el} = \pi \epsilon_0 \frac{R}{z} U^2$$
- R : Tip radius ; U : Potential difference
- For R = 20 nm at a tip-sample distance of z = 0.5 nm and U= 1V,  $F_{el} = 0.9nN$
- Zero bias voltage normally does not correspond to a minimal electrostatic force. → The contact potential difference has to be compensated.

9

### Tip-Sample Forces

Total force on the force sensor (cantilever) = sum of all forces.

Reference: Intermolecular and surface forces (2011) by Jacob N. Israelachvili

10

### Force Sensors

You must feel the force around you.

11

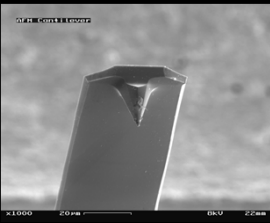
### Force Measurement

The first determination of the constant G in 1798 by Henry Cavendish

©Wikipedia 12

### Force Sensors for AFM : Cantilevers

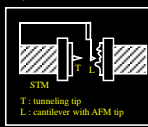
- Hooke's Law  
 $F = k\Delta z$
- Spring constant  $k$ :  
 $k = \frac{E_y w t^3}{4L^3}$   
 typical values: 0.01 - 100 N/m  
 Young's modulus  $E_y \sim 10^{12}$  N/m<sup>2</sup>
- Resonant frequency  $f_0$ :  
 $f_0 = \frac{1}{2\pi} \sqrt{\frac{k}{m_{eff}}}$   
 typical values: 7 - 500 kHz



©Wikipedia

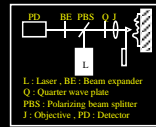
### Deflection Sensors

**Tunneling current**  
 Phys. Rev. Lett. 56, 930 (1986).



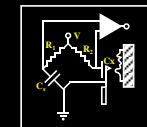
STM  
 T: tunneling tip  
 L: cantilever with AFM tip

**Optical interferometer**  
 J. Vac. Sci. Technol. A 6, 266 (1987).



L: Laser, BE: Beam expander  
 Q: Quarter wave plate  
 PBS: Polarizing beam splitter  
 J: Objective, PD: Detector

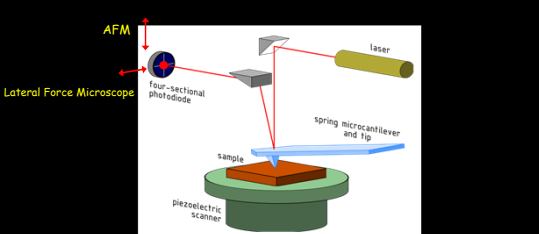
**Capacitive detection**  
 J. Vac. Sci. Technol. A 8, 383 (1990).



Mostly obsolete from today's AFMs.

### Deflection Sensors : Optical Beam Deflection

Most widely used in commercial AFM



Lateral Force Microscope  
 AFM  
 four-sectional photodiode  
 laser  
 spring microcantilever and tip  
 sample  
 piezoelectric scanner

G. Meyer *et al.*, APL 53, 1045 (1988).

### Deflection Sensors : Fiber Optic Interferometer

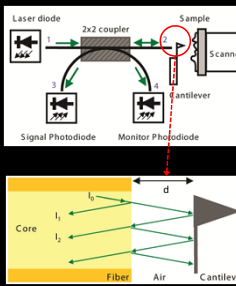
**Fresnel Reflection**

$$\frac{I_1}{I_0} = \left( \frac{n_{core} - n_{air}}{n_{core} + n_{air}} \right)^2 \sim 4\%$$

**Interference :**

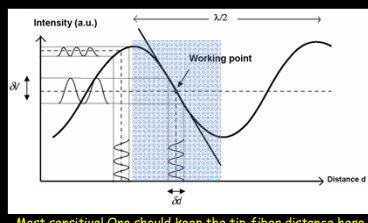
$$I_{total} \sim I_1 + I_2 + 2\sqrt{I_1 I_2} \cos\left(\frac{4\pi d}{\lambda}\right)$$

Great for low temperature!



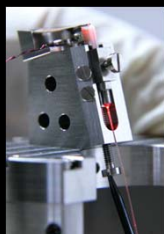
Laser diode  
 2x2 coupler  
 Sample  
 Scanner  
 Cantilever  
 Signal Photodiode  
 Monitor Photodiode

### Deflection Sensors : Fiber Optic Interferometer



Intensity (a.u.)  
 $\lambda/2$   
 Working point  
 Distance  $d$

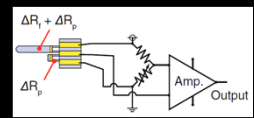
Most sensitive! One should keep the tip-fiber distance here. Practically, it will be fine-tuned by a piezo.



### Deflection Sensors : Self-sensing Methods

**Piezo-resistive detection**

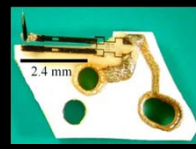
- Self-sensing
- Doped Si
- Low Q

$$V_{out} = \frac{\frac{\Delta R_f}{R}}{2\left(2 + \frac{\Delta R_f + 2\Delta R_p}{R}\right)} \cong \frac{\Delta R_f}{4R} V_{in}$$


M. Tortorese *et al.*, APL 62, 834 (1993)  
 Uijin G Jung *et al.*, J. Micromech. Microeng. 23, 045015 (2013)

**Tuning fork detection**

- Used in non-contact attractive force region.
- $f_0 = 2^{15}$  Hz
- Frequency-modulated operation



Giessibl, Appl. Phys. Lett. 73, 3956 (1998)

### Operation Modes for Topography

Feedback on the oscillation amplitude?

19

### Contact Mode Operation

- Repulsive force region
- Slow scan rate.
- Local deformations or destructions of the sample surface.
- Tip wear issue

F = constant

z = constant

Mica in air, 5 nm, ©Veeco

20

### Dynamic Operation of AFM

- Cantilever is driven at its resonance:

$$m\ddot{z} + \frac{m\omega_0}{Q}\dot{z} + m\omega_0^2 z = F\cos\omega_d t$$

- The particular solution is  $z = z_c + z_p$
- Transient state:

$$z_c = [A_1 \exp\left(-\frac{\omega_0^2}{4Q^2} - \omega_0^2 t\right) + A_2 \exp\left(-\frac{\omega_0^2}{4Q^2} - \omega_0^2 t\right) \cdot \exp\left(-\frac{\omega_0}{2Q} t\right)]$$

- Steady state:

$$z_p = A\cos(\omega_d t - \delta)$$

where  $\delta = \tan^{-1}\left(\frac{\omega_d \omega_0}{Q(\omega_0^2 - \omega_d^2)}\right)$

$$A = \frac{A_0(\omega_d/\omega_0)}{\sqrt{1 + Q^2\left(\frac{\omega_0}{\omega_d} - \frac{\omega_d}{\omega_0}\right)^2}}$$

21

### Dynamic Operation of AFM

- In a presence of force:  $k_{eff} = k - \frac{\partial F}{\partial z}$
- The shift in resonance frequency:

$$\omega = \omega_0 \sqrt{1 - \frac{1}{k} \frac{\partial F}{\partial z}} \approx \omega_0 \left(1 - \frac{1}{2k} \frac{\partial F}{\partial z}\right)$$

- The phase shift:  $\Delta\delta = -\frac{Q}{k} \frac{\partial F}{\partial z}$
- The settle time for amplitude:  $\tau = \frac{2Q}{\omega_0}$
- High Q cantilever enhances the sensitivity but responds slower with amplitude detection (slope detection).
- Frequency modulation is used for high Q situation, especially in vacuum.

©Veeco

22

### Dynamic Operation of AFM: Frequency Modulation

- Feedback loop 1: The cantilever oscillation is controlled at the resonance with the same amplitude by tracking the phase shift.
- Feedback loop 2: The tip-sample distance is controlled to keep the frequency shift constant and hence the same tip-surface force.

T. R. Albrecht et al., J. Appl. Phys. 69, 668 (1991)  
Franz J. Giessibl, Rev. Mod. Phys. 75, 949 (2003)

23

### Limits of Force Sensitivity

- A cantilever in equilibrium with a bath of temperature, T has a energy expectation value for each mode equal to  $k_B T/2$ .

$$\frac{1}{2} k \langle A^2 \rangle = \frac{1}{2} k_B T$$

- Minimum detectable force due to thermal fluctuation:

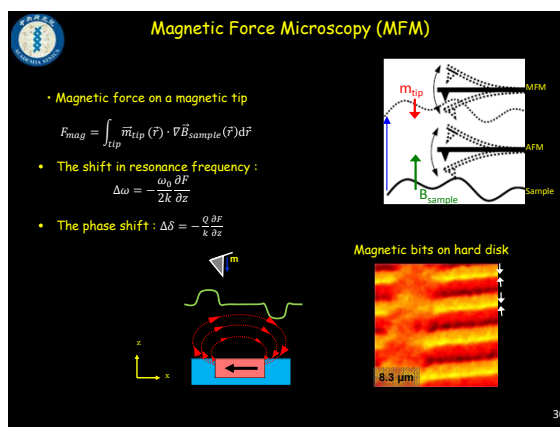
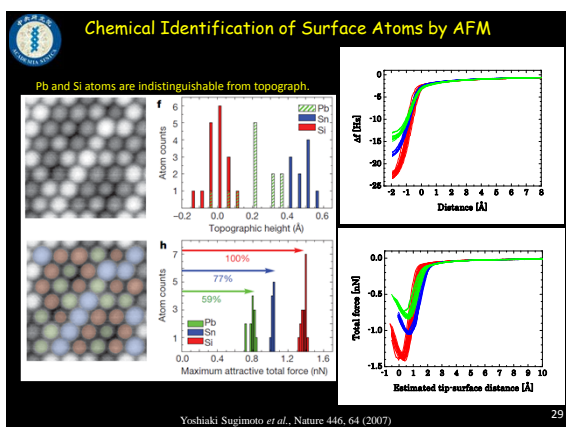
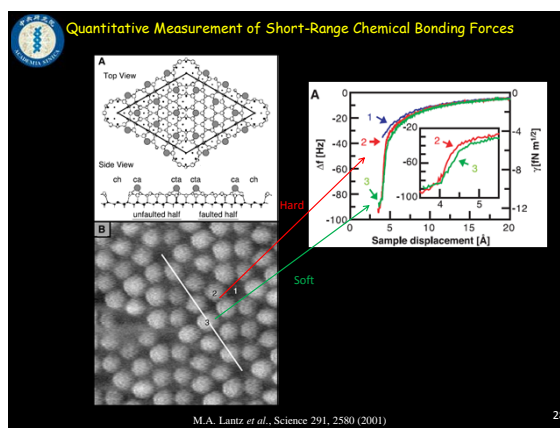
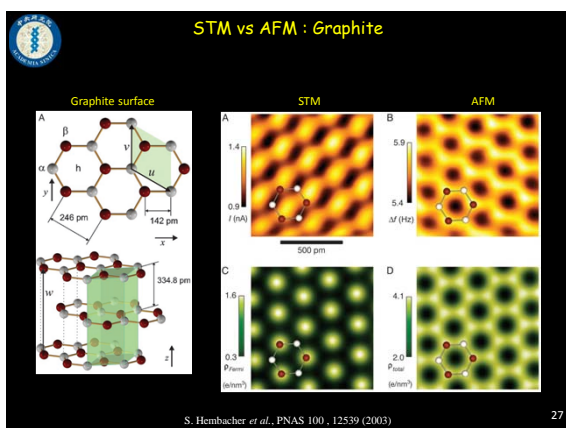
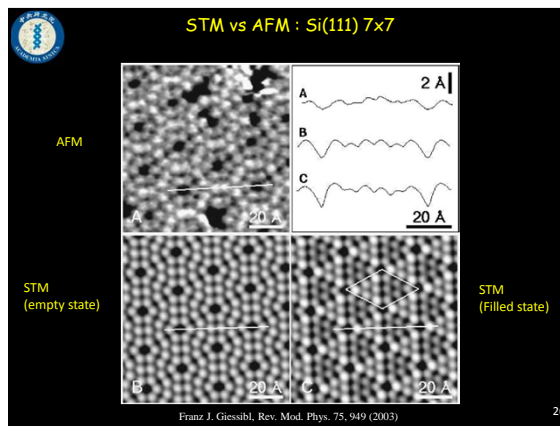
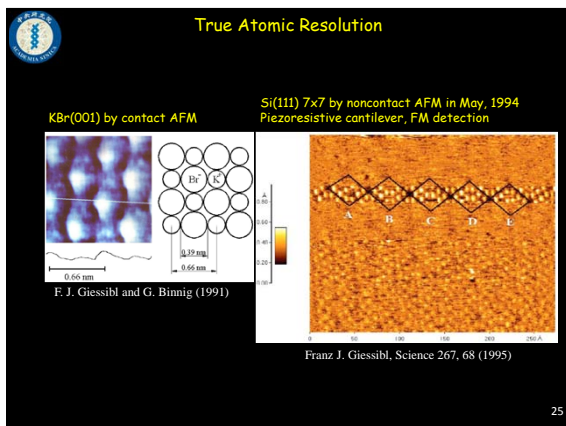
$$\frac{\partial F_z}{\partial z} = \frac{1}{A} \sqrt{\frac{4Bk_B T k}{Q\omega_0}}$$

, B=measurement bandwidth

- Optimization:
  1. Higher Q
  2. Higher resonance frequency
  3. Lower temperature
  4. Amplitude?
  5. Softer cantilever?
- Tuning fork !!!  
 $f_0 \sim 32\text{kHz}$ ,  $k \sim 1800\text{N/m}$ ,  $Q \sim 50000$  in vacuum  
 Noncontact mode operation.

Y. Martin et al., J. Appl. Phys. 61, 4723 (1987)  
Franz J. Giessibl, Rev. Mod. Phys. 75, 949 (2003)

24



### Magnetic Force Microscopy (MFM)

Out-of-plane magnetization

$\text{La}_{2-x}\text{Sr}_{1+x}\text{Mn}_2\text{O}_7, x=0.32$   
 Sample: Dr. J. Goodenough @ UT Austin  
 T=30K

18  $\mu\text{m}$

T.-M. Chuang *et al.*, RSI 78, 053710 (2007)  
 Junwei Huang *et al.*, PRB 77, 024405 (2008)

31

### Electrostatic Force Microscopy (EFM)

- The shift in resonance frequency:  $\Delta\omega = -\frac{\omega_0}{2k} \frac{\partial F}{\partial z}$
- The phase shift:  $\Delta\delta = -\frac{Q}{k} \frac{\partial F}{\partial z}$

PZT film

©Bruker

©Park AFM

32

### Atomic Manipulation by AFM

Sn on Si(111)

Review article:  
 Nature Nanotechnology 4, 803 - 810 (2009)

33

### MIDAS (Micro Imaging Dust Analysis System)

Rosetta orbiter for Comet 67P/Churyumov-Gerasimenko  
 Launched on March 2, 2004.  
 MIDAS is designed to capture and image dust particles in with AFM.

See also AFM on Mars:  
<http://phoenix.lpl.arizona.edu/index.php>

AFM image of a cosmic spherule

Space Science Reviews (2007) 128: 869-904

©NASA

34

### The Need for High Speed AFM

- Mostly in tapping mode, scan size up to 500nm, >7 frames/sec.
- The scan rate is limited by the slowest component:
  - Smaller cantilever for higher resonance
  - Faster scanner
  - Faster feedback and control

Review article:  
 Toshio Ando, Nanotechnology 23, 062001 (2012)...Mostly bio-imaging

AFM manufacturers:  
<http://www.bruker.com/fastscan>  
<http://www.asylumresearch.com/Gallery/CypherFastScanning/CypherFastScanning.shtml>

35

### Imaging of Molecular Dynamics by High-speed AFM

Directly visualized walking Myosin V molecules.  
 Images taken at 146.7 ms / frame

N. Kodera *et al.*, Nature 468, 72 (2010)

36



### Improving AFM Cantilevers

AFM Cantilever with AgGa nanoneedle

©NaugaNeedles

Young's modulus  $\sim 1\text{T Pa}$  for Carbon nanotube!

Review:  
Carbon nanotube tips for AFM  
Nature Nanotechnology 4, 483 (2009)

37

### Improving MFM Cantilevers

Fe-filled Carbon nanotube for MFM

F. Wolny *et al.*, J. Appl. Phys. 104, 064908 (2008)  
F. Wolny *et al.*, Nanotechnology 21 435501 (2010)

38

### Other Magnetic Force Imaging Techniques

- Scanning Hall Probe Microscopy

Direct B measurement  
Limited spatial resolution due to sensor size  
Other means for feedback for topography is required.

Jpn. J. Appl. Phys., 43,777 (2004)

39

### Other Magnetic Force Imaging Techniques

Scanning SQUID Microscopy

The spectral density of the flux noise in the frequency-independent region is  $0.25\mu\Phi_0/\sqrt{\text{Hz}}$  at  $T=0.2\text{K}$ , equivalent to a spin sensitivity of  $\sim 200\mu_B/\sqrt{\text{Hz}}$

RSI 79, 053704 (2008)

40

### AFM Universe

Ch. Gerber, H.P. Lang, Nature Nanotechnology 1, 3 (2006)

41